

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Venkat Selvamanickam, et al.

Title: METALORGANIC CHEMICAL VAPOR DEPOSITION (MOCVD)  
PROCESS AND APPARATUS TO PRODUCE MULTI-LAYER HIGH-  
TEMPERATURE SUPERCONDUCTING (HTS) COATED TAPE

App. No.: 10/602,468      Filed: June 23, 2003

Examiner: Aaron Austin      Group Art Unit: 1775

Customer No.: 34456      Confirmation No.: 2661

Atty. Dkt. No.: 1014-SP156-US

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MS AMENDMENT  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO OFFICE ACTION**

Dear Sir:

In response to the Office Action mailed October 2, 2007, please amend the above-identified application as follows: